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Description automatically generated**

XPS Submission Form – Kratos AXIS Supra+

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| --- | --- | --- | --- | --- |
| **Full Name** |  | | | |
| **Email Address** |  | | | |
| **Phone No.** (optional) |  | | | |
| **University of Glasgow Only** | | | | |
| **Supervisor/Research group** |  | | | |
| **School and College** |  | | | |
| **External Organisations Only** | | | | |
| **Organisation Name** |  | | | |
| **Department** |  | | | |
| **Experiment Details** | | | | |
| **Date Submitted** |  | **Number of Samples** | |  |
| **Techniques Required** (note that for powder samples, only XPS can be chosen) | XPS  UPS (conductive samples only)  XPS imaging  REELS (conductive samples only)  ARXPS  Depth Profiling (please fill in the  Surface etch with XPS relevant section on page 2) | | | |
| **Any additional requirements** *(e.g. elements to look for, data formats)* |  | | | |
| **Sample Details** | | | | |
| **Sample Name** | **Dimensions in mm, including thickness** | **Mass submitted** (if powder) | **Associated hazards (***please attach CoSHH form)* | |
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| **Sample Description**  For each sample, please provide a detailed description that must include the following:  1. What physical form it is (e.g. thin film on substrate, layered device, foil, polymer, powder etc.)  2. What is the structure, what components/layers/films are there and what elements are expected.  3. Is the surface or substrate conductive? Is any of it strongly magnetic?  4. Any other relevant details, including whether any samples are air-sensitive. |
|  |
| **Depth Profiling / Etching Details**  If you wish to include a surface etch or depth profile using the Gas Cluster Ion Source as part of your analysis, please detail your requirements in the box below.  You should include:  1. What are you looking for or expecting to see in a depth profile?   * Are you expecting interfaces between layers/films, chemical changes, or specific elements only appearing at a certain depth? What exactly, how many changes, and to what depth?   2. Is monatomic ion etching or cluster ion etching preferable?   * If you do not know, instead please note if the material is metallic, organic or inorganic, provide a detailed description of the sample |
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